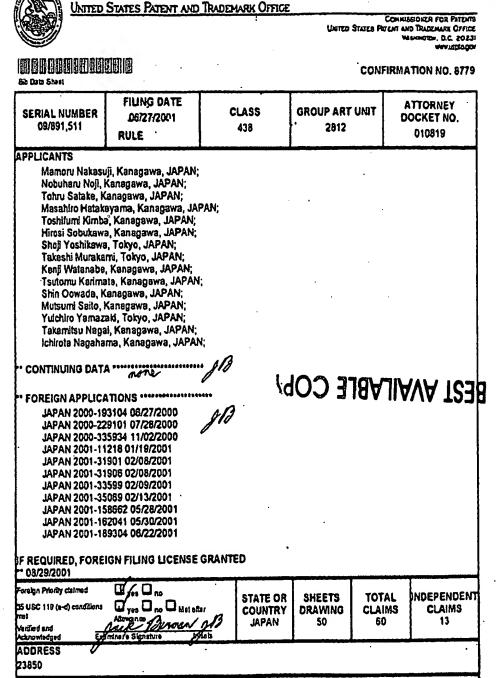
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inspection system by charged particle beam and method of manufacturing devices using the system